

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Toshihide TSUBATA et al. Application No.: 10/595,640 Confirmation No.: 3891 Filing or 371(c) Date: May 2, 2006 Title: TRANSISTOR AND CVD APPARATUS USED TO DEPOSIT GATE INSULATING FILM THEREOF	Art Unit: 2818 Examiner: E. Taylor
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AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated February 5, 2008 and the Advisory Action dated June 4, 2008, the period for response to which has been extended to August 5, 2008, by the accompanying Petition for Three-Month Extension of Time, please amend the above-identified application as follows:

- ☐ **Amendments to the Specification** begin on page of this paper.
- ☒ **Amendments to the Claims** are reflected in the listing of the claims which begins on page **2** of this paper.
- ☐ **Amendments to the Drawings** begin on page of this paper and include an attached replacement sheet. An **Appendix** including the amended drawing figures is attached following page of this paper.
- ☒ **Remarks/Arguments** begin on page **4** of this paper.

Please note, if a box is not checked, then no corresponding amendment is being made.